

FORM PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO P107351-	SERIAL NO Not yet assigned
LIST OF REFERENCES CITED BY APPLICANT <i>(Use several sheets if necessary)</i>			APPLICANT Hiroya KIRIMURA et al.	GROUP 1762
			FILING DATE Concurrently	

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U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NO.	DATE	NAME	CLASS	SUB-CLASS	FILING DATE
MS	AA	4,401,506	Aug. 30, 1983	Otsuka	—	—	
	AB	5,234,843	Aug. 10, 1993	Oyoshi et al.	—	—	
	AC	5,352,291	Oct. 4, 1994	Zhang et al.	—	—	
	AD	5,344,796	Sept. 6, 1994	Shin et al.	—	—	
	AE	5,284,544	2/94	Mizutani et al.	—	—	
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		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION YES NO PART.
MS	AG	2-260627	10-23-90	Japan			X
	AH	9-208389	8-12-97	Japan			X
	AI	5-55194	03-05-93	Japan			X
	AJ	57-160124	10-02-82	Japan			X
	AK	10-149984	06-02-98	Japan			X
	AL	1-231315	09-14-89	Japan			X

OTHER REFERENCES (*Including Author, Title, Date, Pertinent Pages, Etc.*)

MS	AM	"Fast Deposition of Amorphous and Microcrystalline Silicon Films from SiH ₂ Cl ₂ -SiH ₄ -H ₂ by Plasma-Enhanced Chemical Vapor Deposition", Arai et al., Japanese Journal of Applied Physics, Vol. 36, No. 7B, Part 1, July 1, 1997
	AN	PATENT ABSTRACTS OF JAPAN, VOL. 14, NO. 459, October 4, 1990 Publication No. 02188499 (24-07-90)
		PATENT ABSTRACTS OF JAPAN, VOL. 17, NO. 152, March 24, 1993 Publication No. 04318921 (10-11-92)
↓	AO	PATENT ABSTRACTS OF JAPAN, VOL. 95, NO. 5, June 30, 1995 Publication No. 07037822 (07-02-95)

EXAMINER <i>Hiroya Sato</i>	DATE CONSIDERED <i>9/13/2002</i>
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EXAMINER INITIAL		DOCUMENT NO.	DATE	NAME	CLASS	SUB-CLASS	FILING DATE
MA	AA	5,654,043	8/97	Shao et al	—	—	
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		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION YES NO PART.
MA	AG	4-206532	07-28-92	Japan			X
	AH	6-260436	09-16-94	Japan			X
	AI	7-221035	08-18-95	Japan			X
	AJ	0 652 308 A2	05-10-95	European			X
	AK	19 522 923 A1	03-20-97	Germany			X
	AL						

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

AM	
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AO	

EXAMINER <i>Matthew S.</i>	DATE CONSIDERED <i>7/13/2014</i>
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